# LASER MARKING & ENGRAVING

# From application to solution

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Dr. Roland Mayerhofer, Product Marketing Manager Dr. Tissa Gunaratne, Product Line Manager

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- Introduction: from application to solution
- How to select the right laser:
  - Fundamentals: most important parameters for marking and engraving
  - Optical configurations
  - Available laser sources
- Laser marking processes and applications
- Laser micro processes and applications
- How to control the complete process chain?
- System and automation options for complete solutions



# **FROM APPLICATION TO SOLUTION**





# **STEP 1** : **APPLICATION LAB**

- Various laser systems or sub-systems for process development
- Comprehensive measurement equipment for process qualification

### Wavelengths:

UV (355nm), VIS (517, 532nm), NIR (1030-1070nm), IR (9.35-10.6µm)

### **Pulse durations:**

350fs - cw

### **Power levels:**

Up to 1.5kW (IR)





# HOW TO SELECT THE RIGHT LASER FOR A SPECIFIC APPLICATION?



# **NO. 1-6 IMPORTANT LASER PARAMETERS**

- Order of importance
  - Light absorption and heat input optimization:



• Beam quality and optical configuration determine achievable spot size



• Parameter, that help to scale throughput





# **NO. 1 MOST IMPORTANT LASER PARAMETER: LASER WAVELENGTH**

Laser wavelength determines initial absorption in the material



# **NO. 2 MOST IMPORTANT LASER PARAMETER: PULSE WIDTH**

 Pulse width determines ablation rate and quality in surface engraving of metals

Critical pulse duration: determined by lattice heating time

Material	critical pulse duration [ps]
Iron	1.1 – 1.8
Copper	26
Aluminium	7
Titanium	2.6
Nickel	0.3
Platinum	5
Gold	14



#### Critical pulse width



# **PARAMETER BEAM SHAPE: SMART PROTECT TECHNOLOGY**

### I.e. for semiconductor devices with:

- Very thin mold compound encapsulation
- IC substrates with thin laminated solder stop layers
- Dark marking of heat spreaders
- More effective and selective thin film removal
- For IR, green and UV laser markers









# **PROCESSING 3-DIMENSIONAL PARTS**

### Fast Focusing module (FFM)

- Dynamic focus shifter
- Recipe controlled focus setting
- Enables 3D free form marking
- Travel range depends on F-Theta objective





# **TYPICAL LASER TYPES FOR MARKING AND ENGRAVING**

### Powerline E

- End-pumped, solid state Nd:Vanadate lasers
- Short ns-pulses at high peak power



PowerLine E Air 25-1064						
Wavelength	1,064 nm					
Average power	18 W (20 kHz)					
Frequency	cw, 0 – 200 kHz					
Pulse width	20 ns (20 kHz)					
Beam quality M <sup>2</sup>	1.3					

- Powerline F
  - Q-switched fiber laser
  - Fixed or variable pulse width at decent peak power



PowerLine F 20-1064 Varia						
Wavelength	1,060 - 1,070 nm					
Average power	19					
Frequency	2 – 1,000 kHz					
Pulse width	1.5 – 350 ns					
Beam quality M <sup>2</sup>	2.0					

### Powerline USP

- Ps- or fs-lasers hybrid MOPA lasers
- Pulse width ranging from 350 fs to 10 ps, burst mode



PowerLine PS30	
Wavelength	1064 nm
Average power	28 W
Frequency	50 – 5000 kHz
Pulse width	<10 ps
Beam quality M <sup>2</sup>	< 1.3



### LASER MARKING PROCESSES





# **EXACTMARK 230 WITH PS30 LASER - BLACK MARKING**

- High-contrast mark, not sensitive to angle of view
- Indestructible and non-corrosive marking of a broad range of metals
- No fading after multiple autoclaving cycles
- Contamination-free sub-surface mark
- Minimal thermal stress extends applicability on fragile and/or small parts
- No need for post processing, e.g., passivation







# **CORROSION RESISTANT MARKING - BLACK MARKING**

- Short laser pulse durations limit heat affection
- Diffusion of alloy elements is reduced
- Surface oxidation of Cr and Fe significantly reduced
- Formation of nano-structures due to USP laser pulses
- Changes in metal alloy structure minimized





#### Nanosecond mark



Nanosecond laser marking after corrosion test (72h in 50°C warm 5% NaCl saltwater spray test)

#### Picosecond mark



Black-marking LIPSS (laser induced periodic surface structure) under SEM



# **CORROSION RESISTANT MARKING - USP BLACK MARKING**







72h in 50°C warm 5% NaCl salt-water spray test

### **Passivation**





7% Citrisurf 2250, 20 min @ 50°C

### Autoclaving



Steam, >120 °C, 60 min



# **MARKING OF GLASS AND POLYMERS W/ UV NS-LASERS**

- Permanent, direct part marks are mandatory for tracking and traceability.
- Increases patient safety, enhances quality control, improves counterfeit safety





### **MULTI-SIDE MARKING**





# **MARKING BY ENGRAVING**





Post processing mandatory due to the high amount of debris. Discoloration visible due to the heat impact.

### Picosecond



Only slight cleaning required, rougher surface structures within the marking.

### Femtosecond



No post processing or cleaning required, least amount of discoloration.



# **MARKING BY ENGRAVING – SMALLEST FEATURES**

Security features, DMC and traceability marks on various materials (anti-counterfeiting)





Very small codes with cell sizes down to ~5µm can be marked on various materials like metal or glass.

Codes can be marked on glass to be close to invisiblility with bare eye but still readable.



# **APPLICATION MATRIX – LASER MARKING**

	λ = 1,064 nm						$\lambda = 532 \text{ nm}$ $\lambda = 355 \text{ nm}$								
	PL E Air 10	PL E Air 25	PL F 20	PL F 30	PL F 50	PL F 100	PL F 20 Varia	PL F 50 Varia	PL PS 30	PL E 6 QS	PL E 12 QS	PL E 25 SHG	PL E 20 THG	PL E 30 QT	
Plastic Marking (Carbonization)		•	•	•	•		•	•	•				•		
Plastic Marking (Foaming)	٠	٠	•	٠	•		•	•	•						
Plastic Marking (Bleaching)													•	•	
PEEK, PA 6, Nylon											٠	•	•	٠	
Day and Night Design		•					•								
Metal Marking & Engraving			•	٠	•	•	٠	•	•						
Copper Marking												•			
Annealing Marking							•	•							
USP Black Marking									•						
Glass Marking									•		•		•	•	







C

# LASER MICRO PROCESSING APPLICATIONS



![](_page_20_Picture_2.jpeg)

# **SURFACE CLEANING AND STRUCTURING**

- Laser ablation of coatings
  - Paint or organic contaminations
  - Residual material from molding processes
- Laser pre-treatment for adhesion improvement
  - Removal of contaminants (grease, oil, ...)
  - Nano-structuring of metals for improved joining properties with organic materials

![](_page_21_Picture_7.jpeg)

![](_page_21_Picture_8.jpeg)

![](_page_21_Picture_9.jpeg)

# **SURFACE STRUCTURING JOINT IMPLANTS**

- Replace Media Blast for Improved Thermal Spray Coat Adhesion
  - No masking
  - Reduce handling damage
  - Consistent control
  - Minimal strength impact
  - Improved coating adhesion
- Functionalize Surface
  - Promote bone growth
  - Anti-bacterial
  - Modified surface chemistry

![](_page_22_Picture_11.jpeg)

USP processed samples promote bone growth

![](_page_22_Picture_13.jpeg)

# **MULTI-PASS CUTTING OF POLYMER COATINGS ON MEDICAL IMPLANTS AND DEVICES**

- Some medical implants or devices have got a polymer coating or shrink tubing applied to the metal structure
- This coating/shrink tube needs to be cut precisely at specific locations in relation to the strut layout

- Two different Coherent solutions available for such an application, using 30W CO<sub>2</sub> laser (10.6 µm) or fs-Laser SHG (517 nm)
- Vision and pattern recognition sytem required

![](_page_23_Picture_5.jpeg)

# **APPLICATION MATRIX – LASER MICRO PROCESSING**

![](_page_24_Picture_1.jpeg)

![](_page_24_Picture_2.jpeg)

![](_page_24_Picture_3.jpeg)

IERENT	

λ	<i>.</i> = 10,6 μm λ =				= 1,064 nm				$\lambda = 532 \text{ nm}$				$\lambda = 355 \text{ nm}$					
	PL C30	PL E Air 10	PL E Air 25	PL F 20	PL F 30	PL F 50	PL F 100	PL F 20 Var	PL F 50 Var	PL PS 30	Monaco fs- subsist.	PL E 6 QS	PL E 12 QS	PL E 25 SHG	Monaco fs-	<mark>subsist.</mark> PL E 20 тыс	PL E 30 QT	
Deep engraving						•	•	•	•	•	•				•			
Polyimide cutting/drilling															•	•	•	
Polymer cutting/drilling	•									•	•				•			
Coating ablation								•	•	•	•	•	•		•	•	•	
Metal surface structuring										•	•				•			
Polymer structuring										•	•		•		•	•	•	
Tools surface cleaning				•	•	•	•	•	•	•	•							
Thin film ablation										•	•		•		•		•	
Ceramic structuring	•									•	•				•		•	
Glass polishing	•																	
								Dever	auidali	no only	opplie	tion too	t moon	amanda	d		05	

# **APPLICATION CONFIGURATION DONE**

# -> NEXT STEP IS TO LOOK AT THE COMPLETE PROCESS CHAIN

![](_page_25_Picture_2.jpeg)

# **CONTROL THE LASER PROCESS AT VARIOUS STAGES**

![](_page_26_Figure_1.jpeg)

-> Needs a system software to let the process developer or operator set this sequence up in an intuitive way

![](_page_26_Picture_3.jpeg)

# LASER FRAMEWORK SOFTWARE: SETTING UP AN APPLICATION

- The Recipe is the center point of the new LFW concept and allows the process developer to create a sequence of process steps, that are necessary to fulfill a specific laser application.
- The Process step allows setting parameters for the individual steps of a recipe, for example:
  - laser parameter
  - Galvo scanner layout or CNC program
  - variables
  - vision tasks
  - machine I/Os
  - data exchange options
  - etc.

![](_page_27_Picture_10.jpeg)

### C HERENT

# LASER FRAMEWORK SOFTWARE: GENERATE A RECIPE

$\equiv$		pilot off shutter closed equip. state maintenance	READY
Default {1}			Galvo
	Vision		Vision
			Data
+			Live
			Machine
Recipe	<	▶   1/1	Execute
Creation Date			
03.01.2023	maintenance		Edit.
			Delete
	×		
C@HERENT 5.3.27.3	Add or edit a recipe.		03.01.2023   13:29

![](_page_28_Picture_2.jpeg)

# LASER FRAMEWORK SOFTWARE: EXECUTING AN APPLICATION

 The Job – contains all necessary information for the execution of a certain laser processing application. A job includes a recipe and additional data, like number of executions or input variables. Each job has got a unique number assigned, that can also be selected or called by external I/Os.

![](_page_29_Picture_2.jpeg)

![](_page_29_Picture_4.jpeg)

# **CONTROL THE LASER PROCESS: PRE-PROCESS CONTROL**

![](_page_30_Figure_1.jpeg)

![](_page_30_Picture_2.jpeg)

# **PARTVISION – PACKAGES**

Vision and pattern recognition packages for all PowerLine Marking Sub-systems and Systems

BASIC

![](_page_31_Picture_3.jpeg)

**ADVANCED** 

![](_page_31_Picture_5.jpeg)

**ADVANCED +** 

![](_page_31_Picture_7.jpeg)

Consisting of hardware and software features:

- Vision Cube
- Camera
- LED Illumination and controller (Advanced)
- Illumination adapted scanner mirrors
- Pre-assigned Laser FrameWork vision tasks (license-controlled)

![](_page_31_Picture_14.jpeg)

# LASER FRAMEWORK SOFTWARE: DEFINE A VISION TASK

$\equiv$ $\checkmark$	pilot off sh	utter closed equip. state maintenance	READY
Sharpness: 23		$\square \textcircled{0}$	Live
		$\Box$	ROI
100000000000000000000000000000000000000			Teach
			Test
	And the second		Next
Light setup 🗸 🖌		1/3	
Exposure time 10 ms			
C©HERENT 5.3.27.3	Adjust exposure time and light intensity.		03.01.2023   13:41

![](_page_32_Picture_2.jpeg)

# **PRE-PROCESS CONTROL OPTIONS**

- **3D part geometry shape detection** w/ line scan camera and x/z-axes
  - Precise distance measurement
  - Captures point cloud of object surface
  - Accurate detection of workpiece geometry and position
  - Automatic position adjustment of marking layout

![](_page_33_Picture_6.jpeg)

![](_page_33_Picture_7.jpeg)

# **PRE-PROCESS CONTROL OPTIONS**

### Autofocus from image sharpness value

- For TTL camera calibration
- For process developer
- For automatic vision task

#### \*requires LFW controlled z axis \*\* FoV = Field of View

![](_page_34_Figure_6.jpeg)

#### Out of focus: blurry, live FoV\*\*

### In Focus: sharp, crisp live FoV\*\*

![](_page_34_Picture_9.jpeg)

# **PRE-PROCESS CONTROL OPTIONS**

### Autofocus from image sharpness value

- For TTL calibration
- For process developer
- For automatic vision task

![](_page_35_Figure_5.jpeg)

![](_page_35_Picture_6.jpeg)

# **CONTROL THE LASER PROCESS: POST-PROCESS CONTROL**

![](_page_36_Figure_1.jpeg)

### **C** HERENT

# **POST-PROCESS CONTROL OPTIONS**

• Vision: code verification

![](_page_37_Picture_2.jpeg)

 Log code reading results according to ISO standards or print a report

### • Vision: OCR

![](_page_37_Picture_5.jpeg)

Check lasered clear text marking content

### **C** HERENT

# **CONTROL THE LASER PROCESS WITH LASER FRAMEWORK**

![](_page_38_Figure_1.jpeg)

![](_page_38_Picture_2.jpeg)

### **MARKING PROCESS – VIDEO**

# UDI LASER MARKING MADE EASY WITH LASER FRAMEWORK SOFTWARE

# **Preparation and Execution**

![](_page_39_Picture_3.jpeg)

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![](_page_39_Picture_5.jpeg)

# SYSTEM AND AUTOMATION OPTIONS 2

![](_page_40_Picture_1.jpeg)

# **STANDARD SYSTEMS FOR MARKING AND ENGRAVING**

![](_page_41_Figure_1.jpeg)

EasyMark,ExactMark 210ExactMark 230 USPCombiLine XLCombiLine RT800LabelMarkerEasyMark XLExactMark 210 TL/RExactMark 230 WTCombiLine RT1000CombiLine RT1000

AP 530 (dedicated 3d micro processing system with internal robot)

![](_page_41_Picture_4.jpeg)

# **AUTOMATED SYSTEMS - BASED ON UW180 PLATFORM**

![](_page_42_Figure_1.jpeg)

# **AUTOMATION AND PROCESS CONTROL: MARKING**

![](_page_43_Picture_1.jpeg)

![](_page_43_Picture_2.jpeg)

# **AUTOMATION AND PROCESS CONTROL: MARKING**

![](_page_44_Picture_1.jpeg)

![](_page_44_Picture_2.jpeg)

### **AUTOMATION AND PROCESS CONTROL: MARKING AND TEXTURING**

![](_page_45_Picture_1.jpeg)

![](_page_45_Picture_2.jpeg)

# **AUTOMATION AND PROCESS CONTROL: MARKING**

![](_page_46_Picture_1.jpeg)

![](_page_46_Picture_2.jpeg)

# **Automatic Tube** Processing System

![](_page_46_Picture_4.jpeg)

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